

Supporting Information

Solid-source vapor growth and optoelectronic properties of arsenic-based layered group-IV monpnictides

*Syu Kagami*¹, *Noriyuki Urakami*^{1,2, a)}, *Yuichiro Suzuki*¹, and *Yoshio Hashimoto*^{1,2}

¹Department of Electrical and Computer Engineering, Faculty of Engineering,

Shinshu University, 4-17-1 Wakasato, Nagano 380-8533, Japan

²Research Initiative for Supra-Materials,

Shinshu University, 4-17-1 Wakasato, Nagano 380-8533, Japan

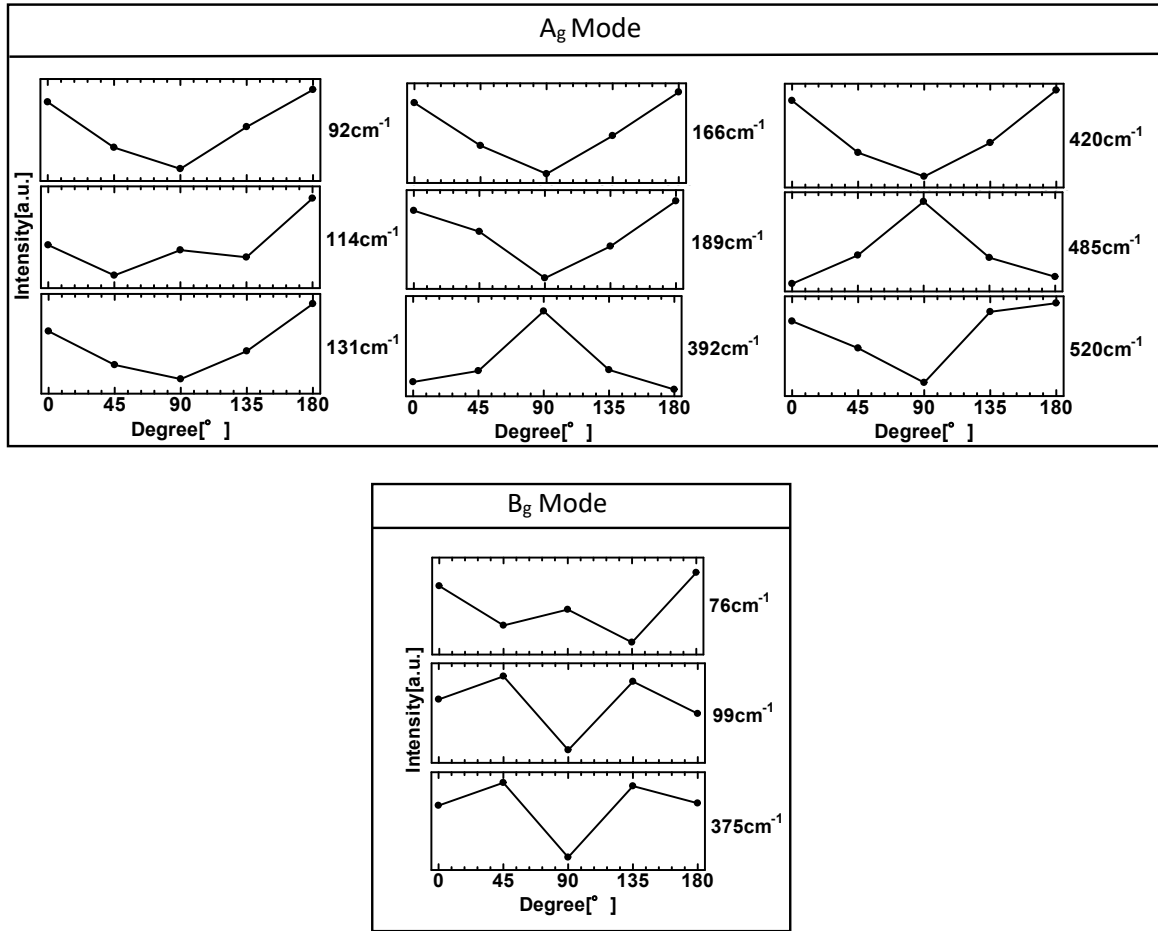


FIG. S1. For SiAs film, angle-dependent Raman intensities for the active vibrations of nine A_g modes and three B_g modes.

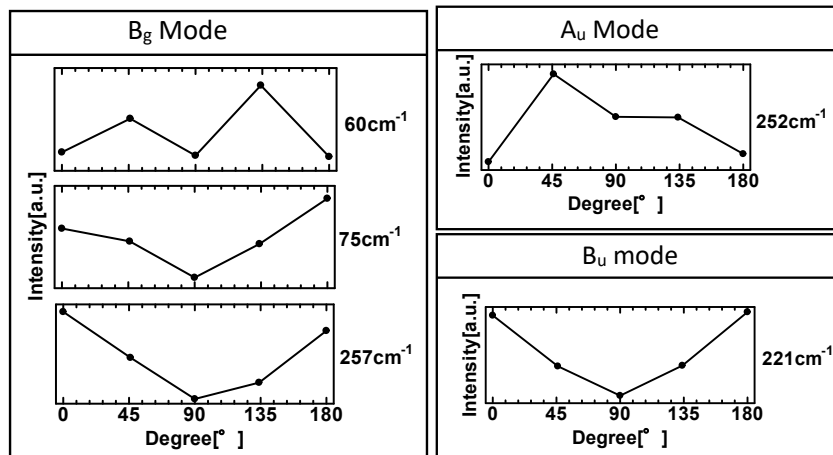
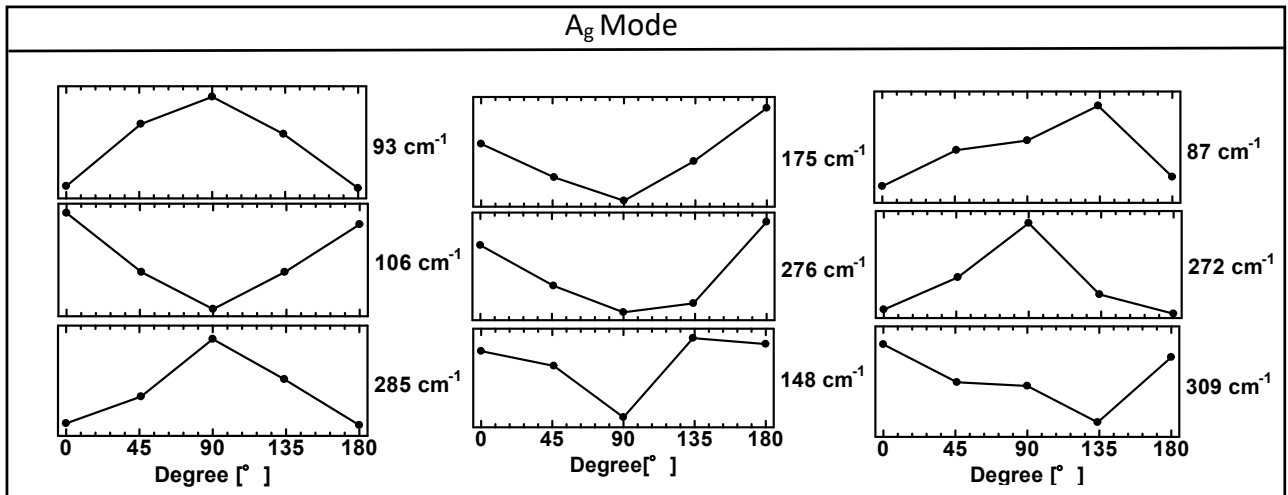
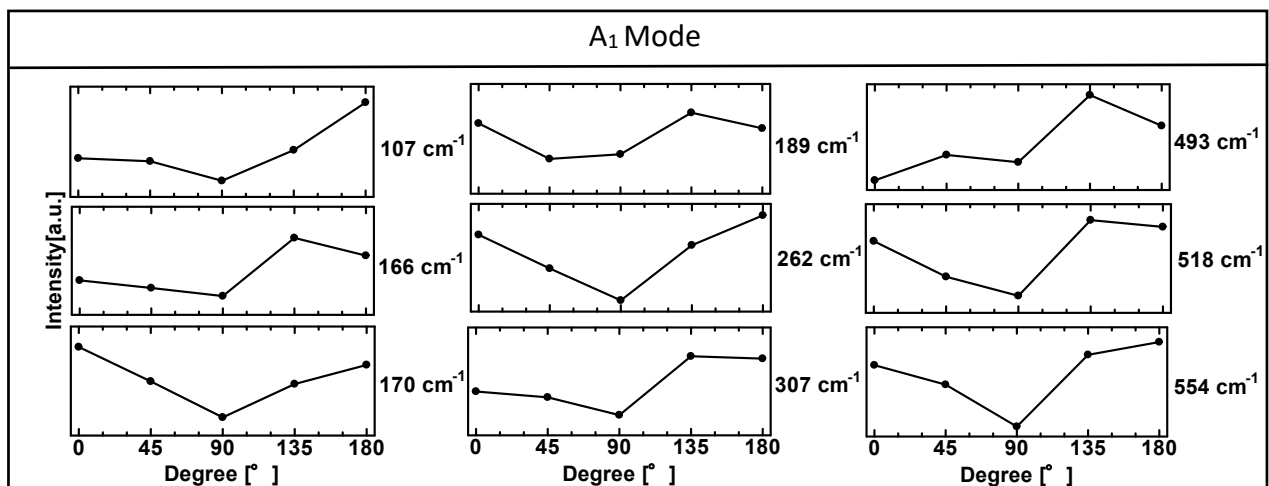
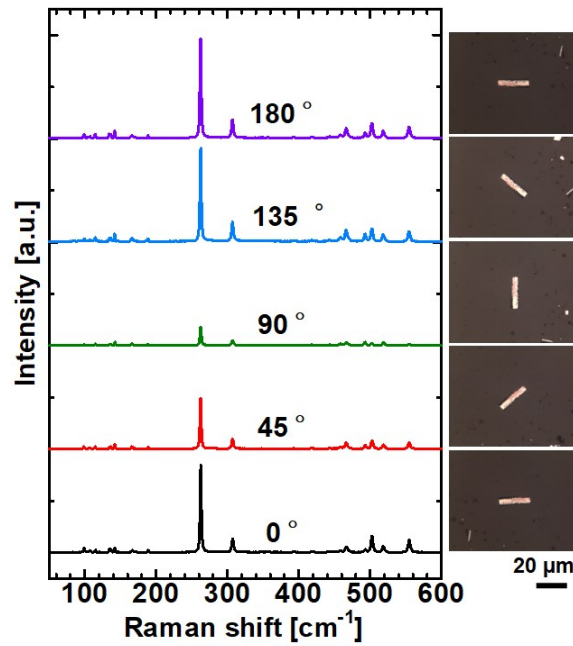
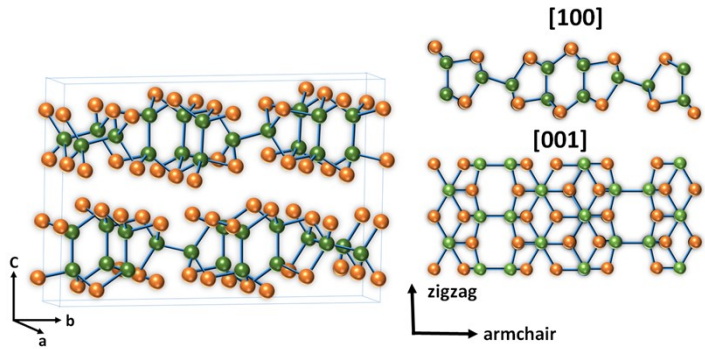
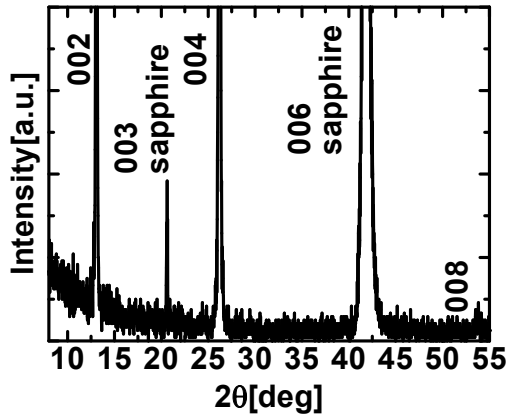
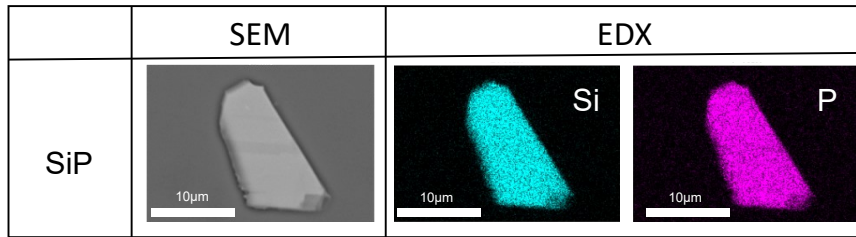


FIG. S2 For SiAs film, angle-dependent Raman intensities for the active vibrations of nine A_g modes and three B_g modes.



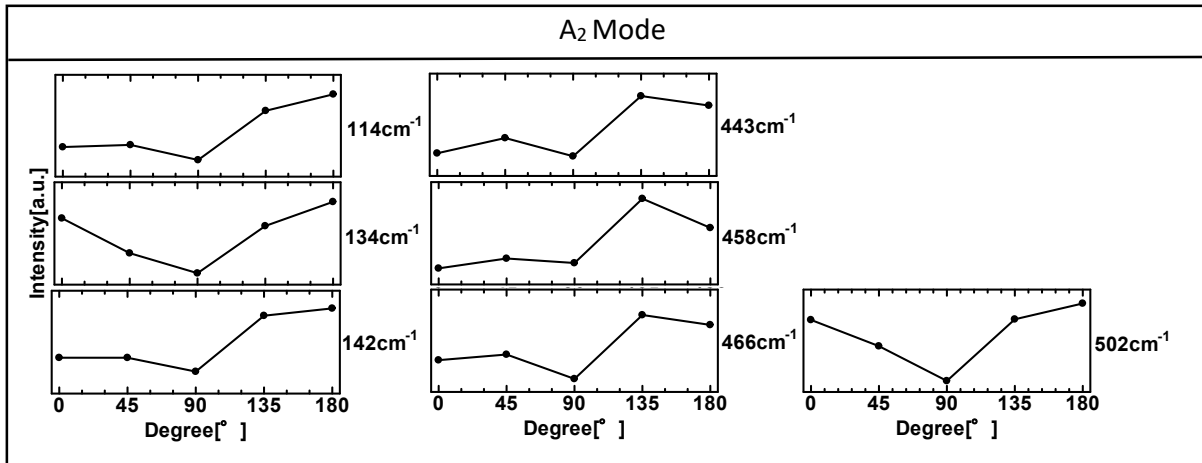
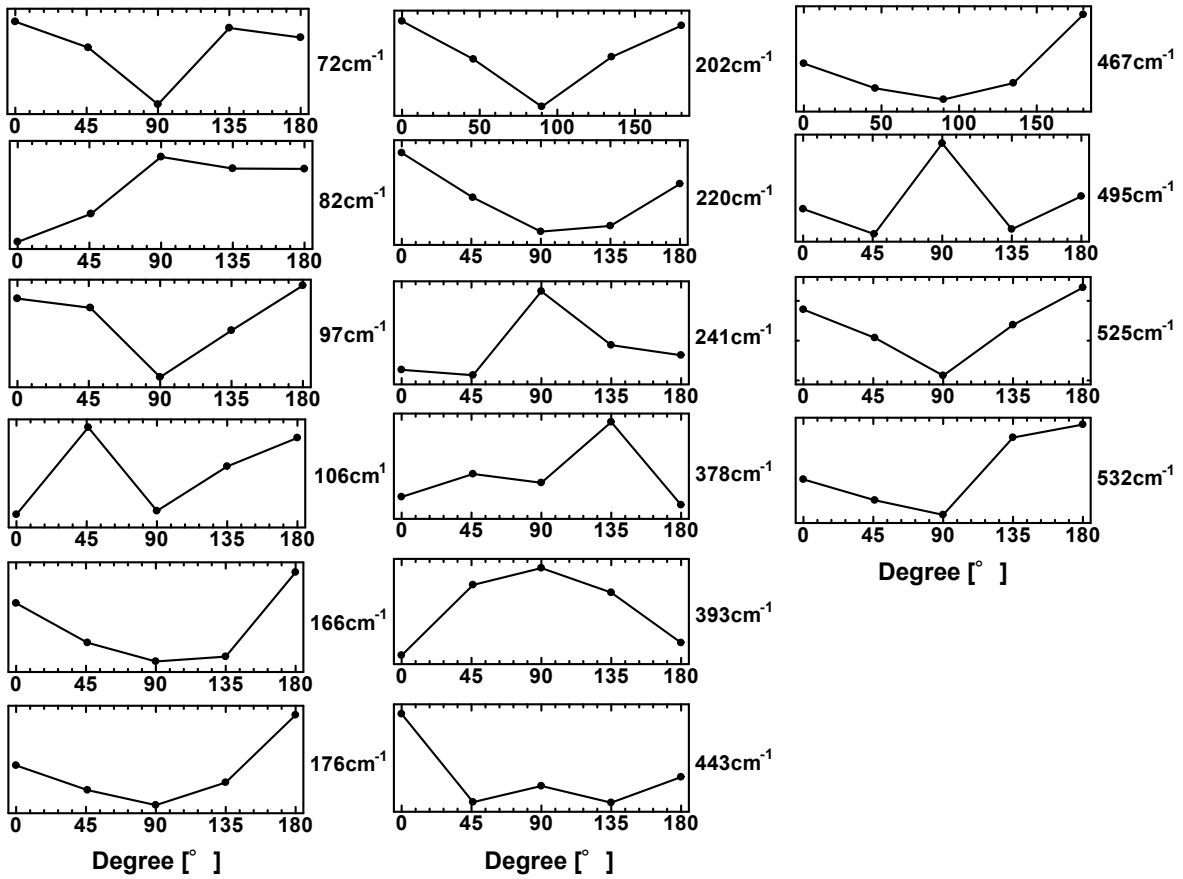
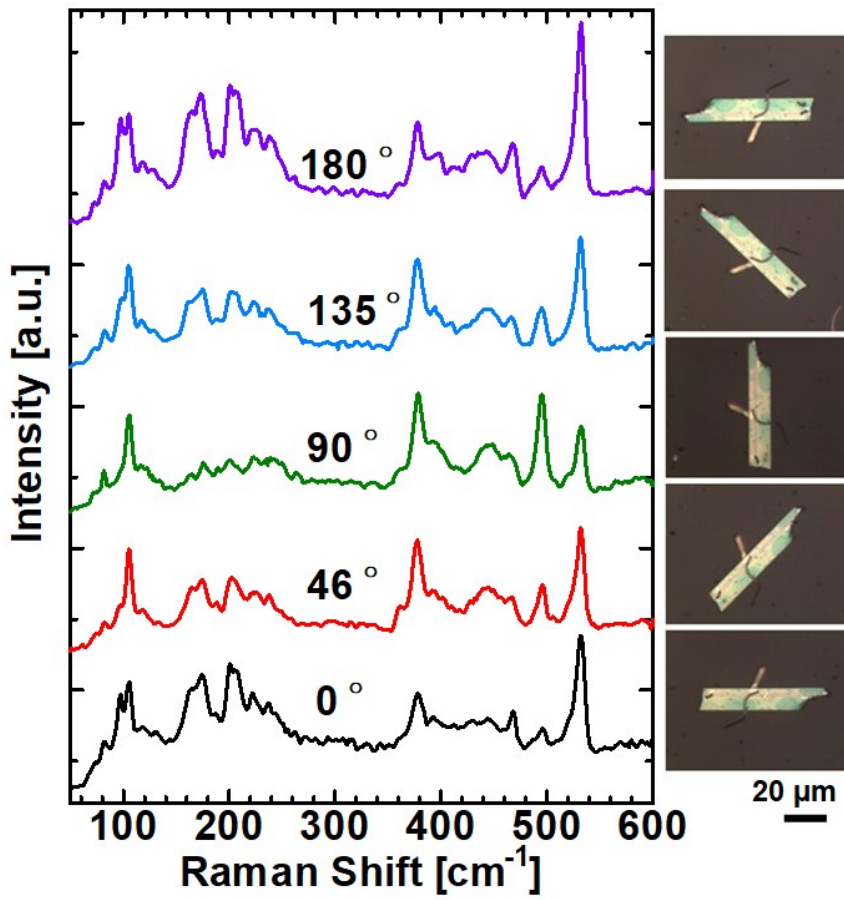
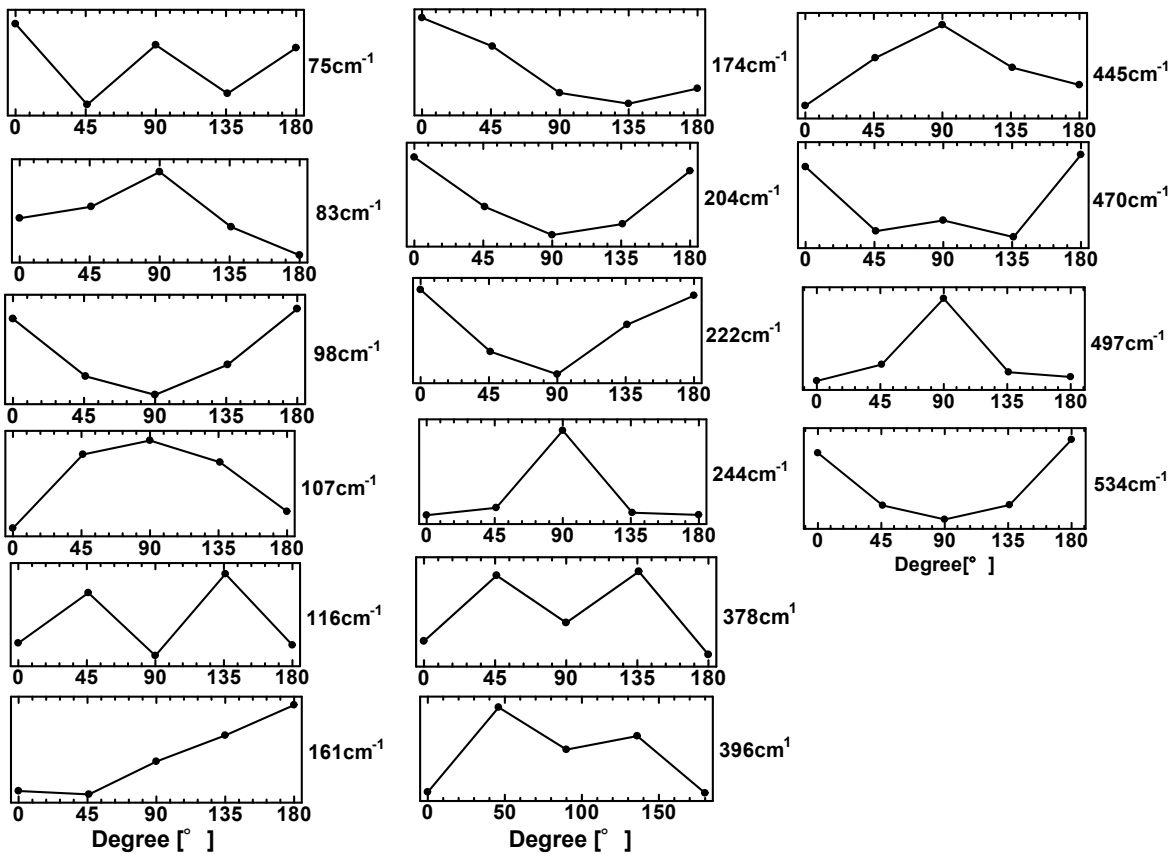
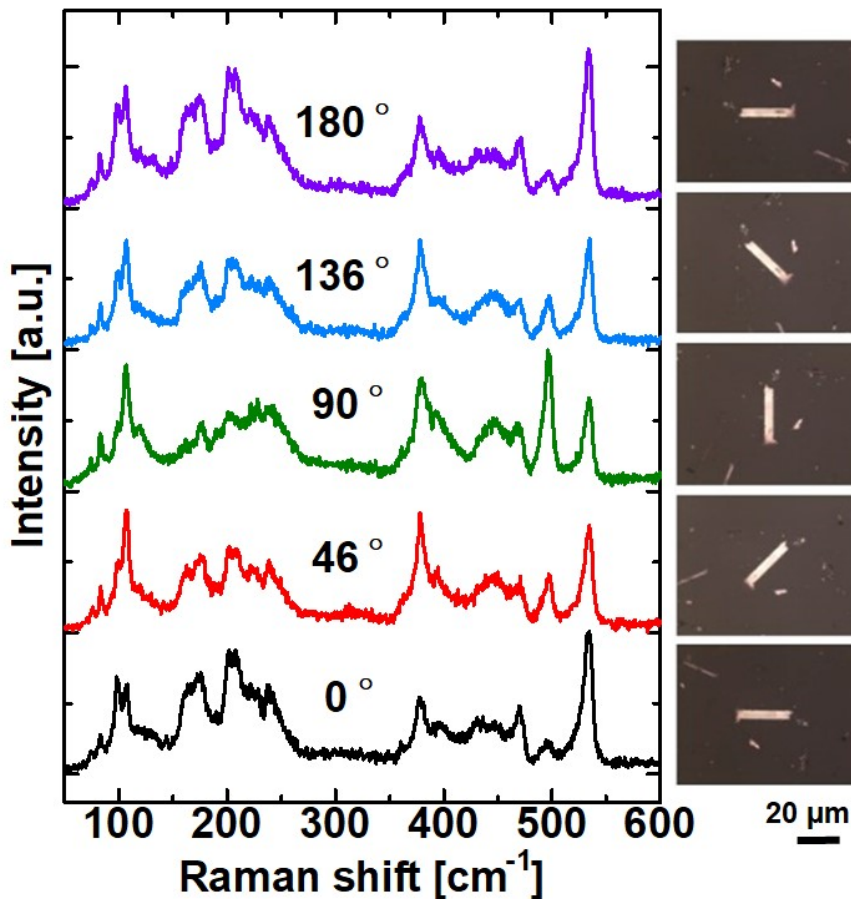


FIG. S3. SEM images with elemental analysis of EDX for SiP. XRD profile of wide-range symmetrical $\omega/2\theta$ scans for SiP film. Side view and top view for the crystal structure of layered SiP. The green and orange balls represent Si and P atoms, respectively. Angle-resolved Raman spectra of SiP rectangular films. The insets show the digital images of the film angle. Angle-dependent Raman intensities for the active vibrations of A_1 modes and A_2 modes.

SiAs_{0.74}P_{0.26}



SiAs_{0.71}P_{0.29}



SiAs_{0.71}P_{0.29}

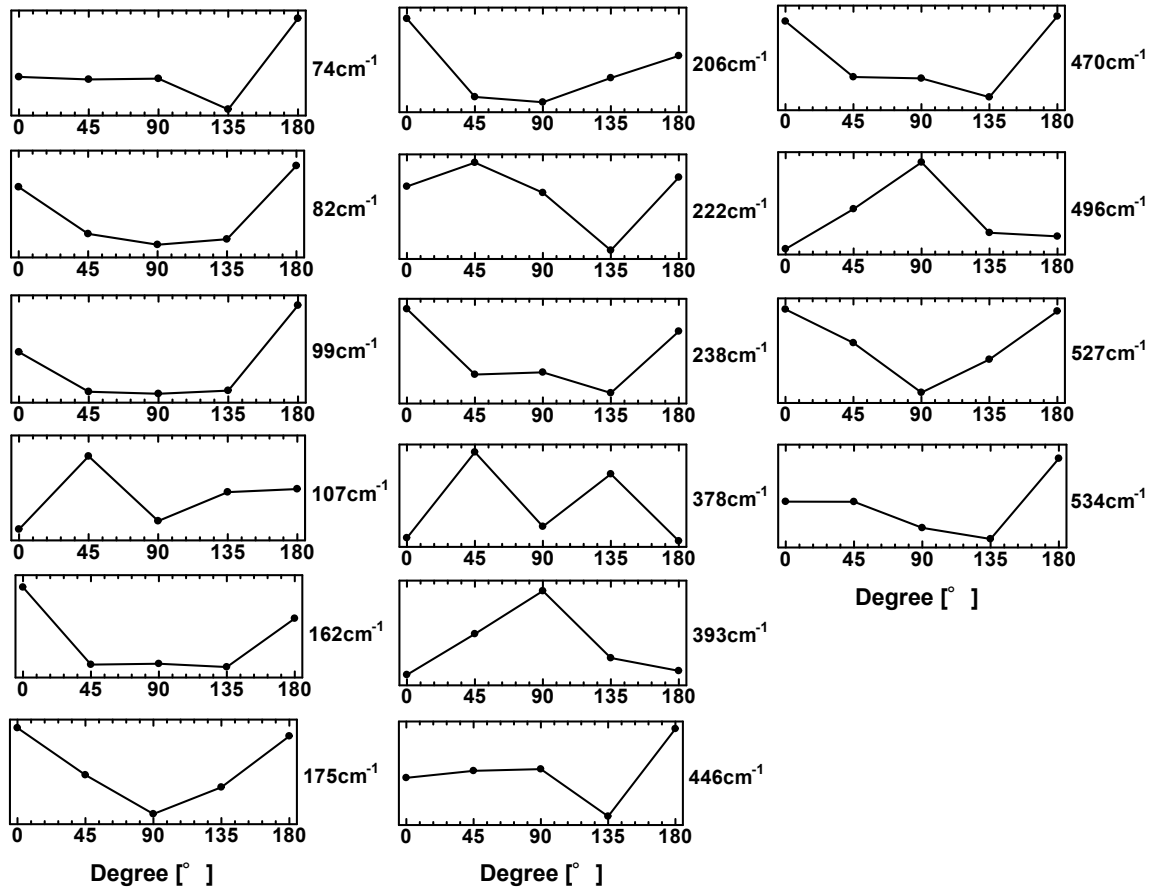
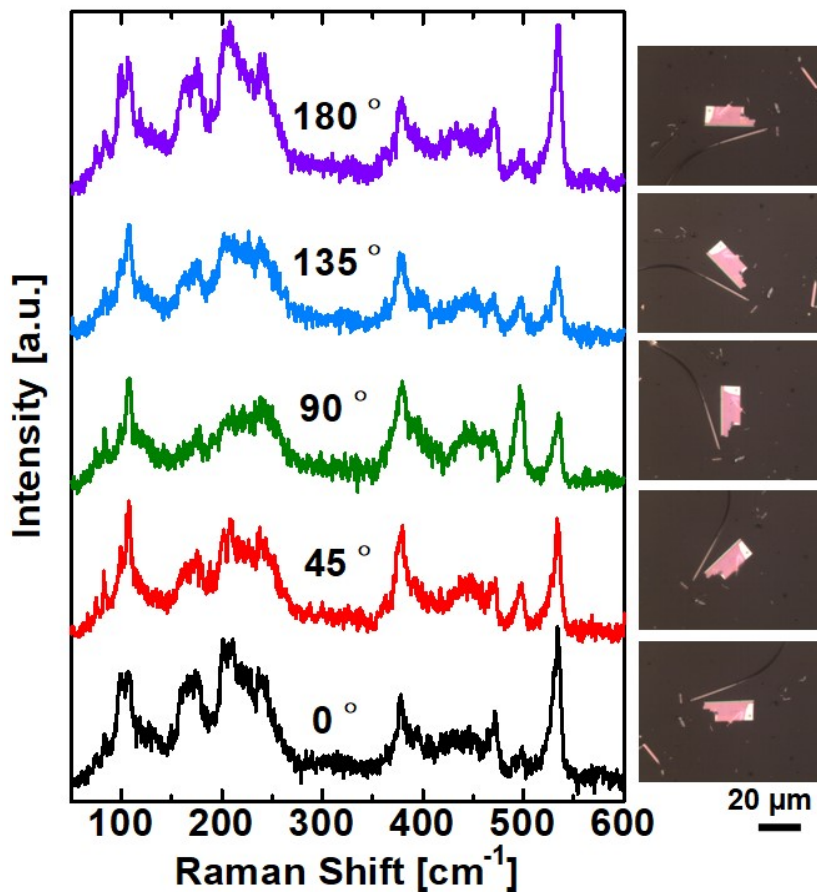
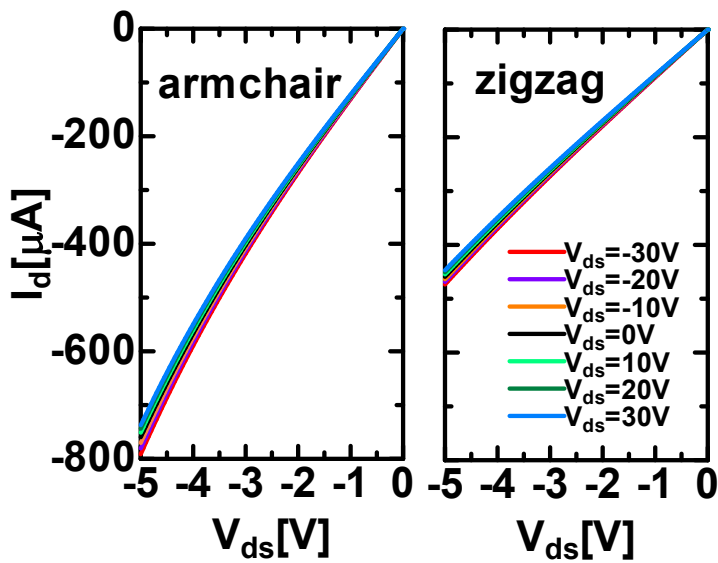


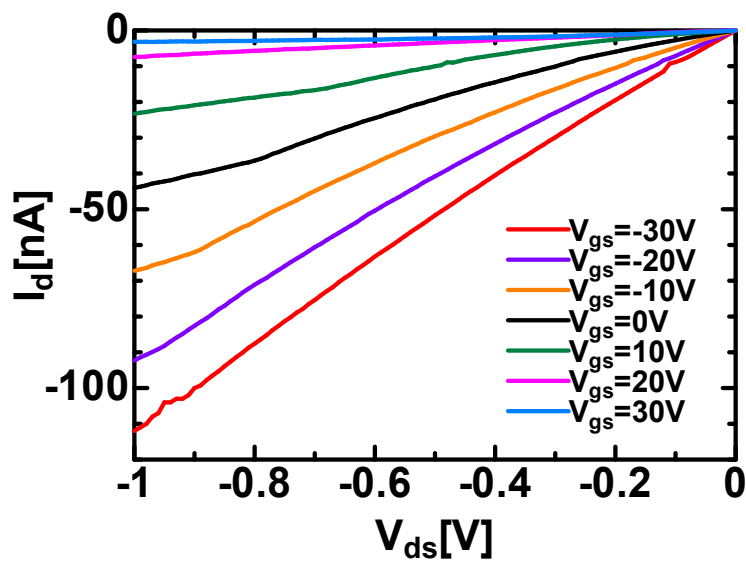
FIG. S4. Angle-resolved Raman spectra of SiAsP rectangular films with the As (P) composition of 0.74 (0.26), 0.71 (0.29) and 0.69 (0.31), respectively. The insets show the digital images of the film angle. Angle-dependent Raman intensities for the active vibrations.

Output characteristics of GeAs FETs

d=173 nm



d=81 nm



$d=28$ nm

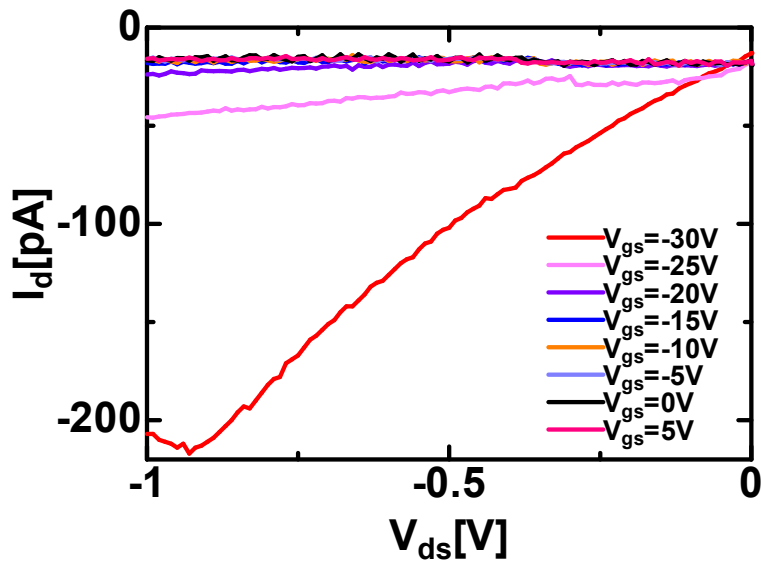


FIG. S5. Output characteristics of GeAs back-gate FETs with various film thickness ($d = 28, 81$ and 173 nm).